

Notice of References Cited	Application/Control No. 09/696,013	Applicant(s)/Patent Under Reexamination YOSHIDA ET AL.	
	Examiner C. Melissa Koslow	Art Unit 1755	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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	B	US-4,495,793	01-1985	Hager, Harold E.	73/31.05
	C	US-5,198,025	03-1993	Dausch, Wilma M.	106/419
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	M	US-			

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	N	WO 00/22202	04-2000	PCT	Yoshida et al	----
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	U	Minegishi et al, "Growth of P-Type Zinc Oxide Films by Chemical Vapor Deposition", Jpn. J. Appl. Phys. Vol. 36, Part 2, No. 11A, 11/97, pp. L1453-55.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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